

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	: Satoru Okamoto	Art Unit	: 1792
Serial No.	: 10/689,617	Examiner	: Mahmoud Dahimene
Filed	: October 22, 2003	Conf. No.	: 4799
Title	: METHOD FOR CLEANING PLASMA ETCHING APPARATUS, METHOD FOR PLASMA ETCHING, AND METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICE		

MAIL STOP RCE

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Applicant requests consideration of the references listed on the attached PTO-1449 form. Under 37 C.F.R. § 1.98 (a)(2)(ii), only copies of foreign patent documents and/or non-patent literature are enclosed. Copies of any listed U.S. patents or U.S. patent application publications can be provided upon request.

This filing is being made with the filing of a Request for Continued Examination and therefore it is believed that no fee is required. Nevertheless, please apply any charges or credits to Deposit Account No. 06-1050.

Respectfully submitted,

Date: March 10, 2008

/Diana DiBerardino/

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